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Docket No.: HOK-0270  
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:  
Tetsuji SHIBATA, et al.

Application No.: 10/529,861

Confirmation No.: 1482

Filed: March 31, 2005

Art Unit: 1763

For: PLASMA TREATMENT APPARATUS,  
METHOD OF PRODUCING REACTION  
VESSAL FOR PLASMA GENERATION, AND  
PLASMA TREATMENT METHOD

Examiner: CROWELL, ANNA M

STATUS INQUIRY

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

It is respectfully requested that the attorney named below be advised of the status of the above-identified application. Please advise us of when we might expect to receive an Office Action from the Patent and Trademark Office.

Applicant believes no fee is due with this response. However, if a fee is due, please charge our Deposit Account No. 18-0013, under Order No. HOK-0270 from which the undersigned is authorized to draw.

Dated: December 5, 2006

Respectfully submitted,

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